

**IN THE SPECIFICATION:**

Please insert the following paragraph before the first line of the Specification:

– This application is a continuation application of Application Serial No. 09/542,799, filed April 4, 2000, currently pending, which claims priority under U.S. Provisional Application No. 60/144,602, filed July 19, 1999. –

Please replace the paragraph beginning at Page 18, line 18 with the following rewritten paragraph:

-- Figure 3 shows how the substrates 326 are being transported over the continuously moving web 322, which is about 50 cm wide to accommodate two substrates 326 positioned transversely across web 322. Figure 3 also shows an arrangement for loading or unloading of the substrates when two substrates are in motion in parallel. The loading and transfer onto moving web 322 or transfer and unloading off of moving web 322 is made via x- and y-movement on the platform 330 which could be a loading or unloading platform depending on placement in the system and direction of motion. For example platform 330 could be a loading platform 142 of the kind shown in Figure 1, or a loading platform 302 of the kind shown in Figure 3, where the x-direction motion is predominantly 327B and the y-direction motion is predominantly 329B. Or, platform 330 could be an unloading platform 144 of the kind shown in Figure 1, or a loading platform 306 of the kind shown in Figure 3, where the x-direction motion is predominantly 327A and the y-direction motion is predominantly 329B. The loading platform 142 may be slightly tilted toward the moving web 122 as shown in Figure 1, and the unloading platform 144 may be slightly tilted away from the moving web 122, as shown in Figure 1. The tilt is adjusted for timely and reliable transfer toward or away from the continuously moving web 122. To begin processing, each substrate 126 is transferred from loading cassette 138 in loading chamber 108 onto loading platform 142 and from there onto moving web 122. After

processing, each substrate 126 is transferred from moving web 122 onto unloading platform 144 and from there to unloading cassette 140 in unloading chamber 110. - -

Please replace the paragraph beginning at Page 20, line 14 with the following rewritten paragraph.

- - Figure 5 A — A is a top view of the lower portion of the system shown in Figure 5, and shows more clearly the relationship between central processing chamber 504, loading chamber 508, unloading chamber 510, loading vacuum valve 518, unloading vacuum valve 520, and vacuum gate valves 512A and 512B which are attached to a vacuum system (not shown) which maintains the desired vacuum in central processing chamber 504. In addition, Figure 5 A — A also clearly shows the relative positions of feed roll stand 524 and second feed roll stand 532, as well as the relative positions of take off roll stand 530 and second take off roll stand 534, with door 513A which provides access to feed roll stands 524 and 532, and door 513B which provides access to take off roll stands 530 and 534.- -

**IN THE CLAIMS:**

Please cancel Claims 2 - 3, 6, 18, and 24 of the prior application without prejudice, and amend the remaining claims as follows:

*Claims not being amended are presented in italics for reference purposes only.*

1. (Once Amended) An apparatus for depositing at least one thin film on a substrate useful in electronic applications, the apparatus comprising:

(a) an in-line continuously moving web for simultaneously transporting a number of substrates to which a thin film of material is to be applied, wherein said moving web is a roll-